

UpNano Nano One 2PP 3D printer Standard Operational procedure AggieFab Texas A&M University



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- SCOPE
  - The purpose of this document is to describe requirements and basic operating instructions for the UpNano NanoOne 3D printing System. The use of this tool is limited to approved processes only.
- SAFETY
  - Be sure that you are trained and signed off to use this equipment.
  - Be sure to keep all doors and protective shields in place before operating this equipment.

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- Refer the materials datasheets for the printing materials.
- If you are unsure about any procedure or indication while operating this equipment be sure to contact a staff member or trainer for assistance.

## Contents

- 1. Scope and Safety
- 2. General work flow
- 3. Overview: resins, characteristics, and post process

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- 4. Checking/Adjusting Tilt Correction Stage
- 5. Think3D
- 6. Printing with fluorescent resins
- 7. Printing with NON-fluorescent resins
- 8. Appendix
  - Objectives, vats, printing mode
  - Substrates & wafer holders
  - Glass substrates and their holders

	Resins		Obje	ctive	<b>.</b>			
	Oils		Feature	Fine	Coarse	Development	Post process	Autofocus
Glass fabrication	UpQuartz	Fused silica (SiO2)		-	5X, 10X	PGMEA (mag stirrer)	<ol> <li>Debinding: ashing oven (air)</li> <li>Sintering : vacuum tube furnace (10^2 mbar)</li> <li>*Al-Oxide plates recommended</li> <li>** temperature profiles avaiable</li> </ol>	ο
High resolution	Upbrix	Ultrahigh- resolution 2.5D material		40X	40X	PGMEA, IPA	-	Ο
	Updraft	Fas	st prototype	All	All	IPA	-	0
Transparent Fast prototype	UpPhoto	High-performance	1.0 0.8 0.6 0.4 0.2 0.0 400 600 800 1000 1200 1400 1600 180C Wavelength (nm)	All	All	IPA	-	0
	Upflow	Low-au Lo	tofluorescence w-viscosity	10, 20, 40X	10, 20, 40X	PGMEA, IPA	UV (365 - 405 nm) ~ 30 min	х
Low auto-fluorescent Bio compatible	Upopto	High optical transparency Ultralow- autofluorescence		10, 20, 40X	10, 20, 40X	PGMEA, IPA	UV (365 - 405 nm) 30 - 60 min	Х
	Upsol	spining	g on substrate 2.5D, 3D	10, 40X	10, 40X	1-propanol	Tesas A SV Roch en for a la composición de la composición de la composición de la composición de la composición	Ο

## **Checking tilt correction stage**



## Checking gap

- try to insert the substrate hold into the top and bottom pieces: X, Y, Z motors
- □ Should be inserted while not too much gap





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## Open 'tilt' tap Click the 'setting' icon

			Clear 2-
ancei			Clear Jo
<b>3</b> *			
Connect to the tilt insert. Disabled if already connected			
ıbstrate: Glass Slide (0.17mm)			$\sim$
🗙 Center Top	Pos	sition	
Left Bottom	X:	0.00 µm	***
	Y:	0.00 µm	
K Right Bottom	Z:	0.00 µm	
		Set Z to cur	rrent
		Goto XY Pos	sition

## Adjust the gap using ONLY arrows NEVER click 'Set Zero' or 'Goto Zero'

Move Motors		? ×
Motor X	Motor Y	Motor Z
<b>†</b>	<b>†</b>	<b>†</b>
•	+	<b>•</b>
Position: -62.2µm	Position: 155.6µm	Position: 164.8µm
Set Zero Goto	Zero	

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## Think 3D – set up parameters



## **Objectives**



- ➤ 5 objectives available
- > Consider resolution, size, and parameters

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Objective	ID	Media	NA	WD (mm)	FOV (mm)	BH (mm)	Max Bottom Up Height (mm)	XY speed (mm/s)	Volume speed (mm^3/s)
5X	Fluar	air	0.25	12.5	2.8	80	3	1200	300
10X	UPLFLN	air	0.3	10	1.4	60	2	600	60
10X	UPLXAPO	air	0.4	3.1	1.4	60	0.7	600	40
20X	UPLSAPO	DH2O	0.7	0.35	0.7	30	0.25	300	2.25
40X	UPLSAPO40XO	Immersol	1.4	0.13	0.35	10	0.15	150	0.25

### Vat (XXL) - air







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## **Printing with fluorescent resins**

1. Open the build room

### Printer: build room opened



## Build room



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2. Screw in an objective



## 3. Select a vat & put resin



## 4. Place the vat



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### 5. Place a stage on the frame



## 6. Place and secure substrate holder



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		NanoOne 1000 Objective: UPLXAPO10X Description: Elapsed Time: - Steps: 0/0 Cancel Pending Jobs Start Oneck 1. UPLXAPO10X Tue Nov 12 15:58:54 2024.thinkage UPLXAPO10X/UpPhoto Tomm Standard Plate/Vat Click 'Send to printer' Job file appears	0% Clear Job Delete 2024-11-12 15:59
Stage	Laser spot	<ol> <li>Click 'on'</li> <li>Set power 0.5 mW or lo</li> <li>Click 'set'</li> <li>Laser spot at the cente</li> </ol>	wer r appears

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New File - 31 Station Line Joint Theory Help Design region region region	Menu deals with the Printer	job file, not stl file	NanoOne 1000 Objective: UPLXAPO10X Description: Focusing Elapsed Time: - Remaining Time: - Steps: 0/0 Cancel	- O × Send to printer  V  O% Clear Job	
		<ul> <li>Autofocus setting popup</li> <li>Check parameters and click 'Sta</li> <li>Advanced</li> <li>Advanced</li> <li>Obsons</li> <li>UpPhote</li> <li>UpPhote</li> <li>UpPhote</li> <li>Start</li> <li>Cancel</li> </ul>	Substrate: Glass Slide (0. 17mm)  Center Top  Left Bottom  Right Bottom  Correct Tit Goto Zero	Position X: 0.00 µm Y: 4285.28 µm Z: 4000.00 µm Set Z to current Goto XY Position	Filt correction Set substrate Double 'Center Top' Click 'Autofocus' Click 'Set Z to current' Repeat for the other points. Repeat the other two
Stage Zero: Center X: -792.543 µm -0.0 Y: -98.84 µm -8,285. Z: 107.241 µm -17,489. Axes: XYZ ✓ Set Point	Velocity Slow Slow Modera te f fast Power: 0.50mW (2) Set Autofocus 200 µm Stop	<ul> <li>9. Increase Z with the slow r</li> <li>10. Click Autofocus, set para</li> <li>11. Perform tilt correction</li> <li>12. Move to center</li> <li>13. Perform final autofocus</li> <li>14. Start printing</li> </ul>	node until the laser sp ameters, and click sta	oot become sm rt	naller

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## **Printing with NON-fluorescent resins**

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### Start with pre-patterned substrate Ex) 1" X 1" glass (500 µm thick)



Mounting substrate on vacuum holder Turn on vacuum pump & Place the substrate



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## **Printing with NON-fluorescent resins**

### Focus at the 1<sup>st</sup> point

C:/Users/AggieFab/Desktop/Users/Sung Oh Woo/LevelingPyramid\_upOPTO\_40x.thinkage - Think3D

# Click 'Tilt tap' and select the 1<sup>st</sup> point **!!!** NO double click



## Appendix

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## Vat mode

- > Combination of various vats and substrates: objective media (oil, air, water) | substrate size
- Printing part height up to 42 mm





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## Bottom up mode

- > Printing into sterile vessels, petri dishes, or any transparent substrates
- Printing from the bottom of the vessel upwards
  - Printed structure height limit because of the scattering of laser through the polymerized resin.



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## **Printing materials selection guide**

# **Printing resins**

for any application

for any	apprication	Updraft	Up <mark>brix</mark>	UPsol	Up <b>thermo</b> Powered by cubicure	Upphoto	UP <b>opto</b>	Upblack	Upflow
	Common Objective	20x,10x	40x	40x,20x	10x,5x	20x,10x,5x	40x,20x,10x	10x	40x,20x,10x
	Fabrication Speed	+++	++	++	++	++	+	++	++
	Highly Transparent						++		+
	Vat Mode	~	~		~	~	~	~	~
	High Aspect Ratio	~	~		~	~	~	~	~
	Low Viscosity		~			~			~
	Low Fluorescence						~	~	~
	Low Transmissive							~	
	Refractive Index Matched		~						
	2.5D Structures		~	~					
	Sub-µm Printing		~	~					
	Overhangs Smaller 90°			~					
	Bio Compatible*				~	~	~	~	~
	High Temperature Stability*	*			~				
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- ➤ 5 objectives available
- Select one of them based on the resolution and total size of the printing structure
- Estimation of printing time is available in the 'Think 3D'
  - Refer the excel file on the desktop, 'Print time estimation.xlsx'



Objective	ID	Media	NA	WD (mm)	FOV (mm)	BH (mm)	Max Bottom Up Height (mm)	XY speed (mm/s)	Volume speed (mm^3/s)
5X	Fluar	air	0.25	12.5	2.8	80	3	1200	300
10X	UPLFLN	air	0.3	10	1.4	60	2	600	60
10X	UPLXAPO	air	0.4	3.1	1.4	60	0.7	600	40
20X	UPLSAPO	DH2O	0.7	0.35	0.7	30	0.25	300	2.25
40X	UPLSAPO40XO	Immersol	1.4	0.13	0.35	10	0.15	150	0.25

## **Objectives (2/3)**

		BOTTOM UP	VAT	VERTICAL	HORIZONTAL		
	40x	≤ <b>150</b> µm		> <b>0.8</b> µm	> <b>1.8</b> µm	<b>150</b> mm/s	<b>0.25</b> mm³/h
CTIVES	20x	<b>≤ 250</b> µm	DADT	> <b>2.5</b> µm	> <b>5</b> µm	<b>300</b> mm/s	<b>2.25</b> mm³/h
ard obje	10x NA0.4	≤ <b>700</b> μm	HEIGHT UP TO	> <b>5</b> µm	> <b>20</b> µm	<b>600</b> mm/s	<b>40</b> mm³/h
STAND/	10x NA0.3	≤ <b>2</b> mm		> <b>7</b> µm	> <b>50</b> µm	<b>600</b> mm/s	<b>60</b> mm³/h
	5x	≤ <b>3</b> mm		> <b>12.5</b> µm	> <b>200</b> µm	<b>1,200</b> mm/s	<b>300</b> mm³/h

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## **Objectives (3/3)**

		NA NA	WD	FOV	BH	IM	FS	FS
	40x	1.4	0.13	0.35	10	oil	≤ <b>220</b> nm	≤ <b>550</b> nm
CTIVES	20x	0.7	0.35	0.7	30	water	≤ <b>420</b> nm	≤ <b>2.9</b> μm
ard obje	10x NA0.4	0.4	3.1	1.4	60	air	≤ <b>730</b> nm	≤ <b>9.2</b> µm
STAND	10x NA0.3	0.3	10	1.4	60	air	<b>≤ 980</b> nm	≤ <b>16.4</b> µm
	5x	0.25	12.5	2.8	80	air	≤ <b>1.2</b> µm	≤ <b>23</b> µm

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- Numerical Aperture | WD – Working Distance [mm] | FOV – Field of View [mm] | BH – Block Height [µm] | IM – Immersion Media | FS – min. Feature Size

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## **Stages and wafer holders:**

### Tilt correction stage

– various sample substrate holders



### Tilt correction 4"stage



### Various sample substrate holders



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## **Glass substrate & holders**

### Glass substrates

- Square: 10, 20, 40 mm<sup>2</sup>
- Round: 1 inch in diameter



### Glass substrate holder





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## Substrate holder manipulation

### Holding sample

- Place the substrate holder
- Rotate the knob clockwise
- Sample holding square wider
- Place a glass substrate
- Bring back the holder using knob



### **Knob operation**

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- Move the stage holder along +X
- Lift up the metal pieces, popping up the glass substrate



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#### **Approvals:**

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Gandra G Malhotra

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Printing technique with the Non-fluorescent resin added	Dr. Sung Oh Woo	03/05/2025





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